

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	2	"US 20060290747"	US-PGPUB; USPAT; USOCR; DERWENT	OR	ON	2008/08/13 13:41
S2	1	"11157073".pn.	JPO	OR	ON	2008/08/13 14:04
S3	9	("11157073" "10286960" "200363000" "2000141644" "2003110160" "10211701" "10226071" "11077999" "11291493" "2000246896").pn.	JPO	OR	ON	2008/08/13 14:30
S6	16	347/68.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and electrode and (insulation insulating insulated) with (inorganic)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 15:12
S7	7	347/68.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and electrode and (insulation insulating insulated) with (inorganic) and ((aluminum tantalum) adj2 oxide)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 15:13
S8	3	(channel and pressure adj3 chamber and nozzle and piezoelectric and electrode and vibration adj2 plate and insulating adj2 film).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 15:32
S10	16	347/68.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and electrode and (insulation insulating insulated) with (inorganic)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:03
S11	2	"US 20030025769"	US-PGPUB; USPAT; USOCR; DERWENT	OR	ON	2008/08/13 16:06
S12	4	("20030025769" "6431690").pn.	US-PGPUB; USPAT; USOCR; DERWENT	OR	ON	2008/08/13 16:10
S13	2	("5896149").pn.	US-PGPUB; USPAT; USOCR; DERWENT	OR	ON	2008/08/13 16:11

S14	14	347/68,70,71,72,64,63,54.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and electrode and (insulation insulating insulated) with (inorganic) and (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O.sub.3"))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:16
S15	298	347/68,70,71,72,64,63,54.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and electrode and (insulation insulating insulated) near3 film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:20
S16	161	347/68,70,71,72,64,63,54.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and (upper and lower) near3 electrode and (insulation insulating insulated) near3 film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:21
S17	11	347/68,70,71,72,64,63,54.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and (upper and lower) near3 electrode and (insulation insulating insulated) near3 film same inorganic	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:22
S18	324	347/68,70,71,72,64,63,54.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) same electrode and ((protective protection insulation insulating insulated) near3 (layer film)) with (pzt piezo\$)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:28
S19	93	((protective protection insulation insulating insulated) near3 (layer film)) with (inorganic near2 amorphous)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:29
S20	5	((protective protection insulation insulating insulated) near3 (layer film)) with (inorganic near2 amorphous) same (pzt piezo\$)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:29
S23	54	(pzt piezo\$) same ((protective protection insulation insulating insulated) near3 (layer film)) with (inorganic) and (print\$4head record \$4head ((ink\$1jet record\$3 print\$3) adj2 head) printer)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:35
S24	3	("6494567"   "6929355"   "7008048").PN. OR ("7273268").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2008/08/13 16:38

S25	1	29/25.35.ccls. and (pressure near3 (chamber channel)) same (nozzle orifice) and (pzt piezo\$ tranducer) and (upper and lower) near3 electrode and (insulation insulating insulated) near3 film same inorganic	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 16:40
S26	2210	347/68.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 18:38
S27	763	347/70.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 18:38
S28	9	("4866460"   "5818482"   "5933170"   "6158847"   "6217158"   "6231169").PN. OR ("6443566"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2008/08/13 18:40
S29	213	347/70.ccls. and ((protective protection insulation insulating insulated) near3 (layer film))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 18:43
S30	421	347/68.ccls. and ((protective protection insulation insulating insulated) near3 (layer film))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 18:44
S31	530	347/68,70.ccls. and ((protective protection insulation insulating insulated) near3 (layer film)) and electrode and (pzt piezoelectric piezo-electric)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 18:45
S32	7	("20040114004" "6520633" "6883906" "6099111").pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 19:01
S33	8	("20020036667" "6270193" "6572223" "6491384").pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/13 19:17

S34	2	("20020080213").pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:14
S35	11	("5124716"   "5212496"   "5265315" "5376857"   "5530465"   "5610643" "5631463"   "5719607"   "5831299" "5984458"   "6022458").PN. OR ("7101026").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2008/08/14 13:15
S36	40	347/68,70.ccls. and ((protective protection insulation insulating insulated) near3 (layer film)) with ((inorganic) (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O. sub.3"))))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:17
S37	112	347/68,70.ccls. and (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O.sub.3"))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:18
S38	27	347/68,70.ccls. and ((protective protection insulation insulating insulated) near3 (layer film)) near4 ((inorganic) (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O. sub.3"))))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:18
S39	6	347/68,70.ccls. and ((protective protection insulation insulating insulated) near3 (layer film)) near4 (inorganic) and (inorganic with (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O.sub.3"))))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:22
S41	12	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) near4 (inorganic) and (inorganic with (((aluminum tantalum) adj2 oxide) ("Al.sub.2" adj "O.sub.3"))))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:23
S43	102	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) near4 (density)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:43
S44	1	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) near4 (young\$2 adj2 modulus with elasticity)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:44

S45	38	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) near4 ((young\$2 adj2 modulus) (tensile adj2 (stress strain)) (modulus adj2 elasticity))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:46
S46	59	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) same ((young\$2 adj2 modulus) (tensile adj2 (stress strain)) (modulus adj2 elasticity)) not S45	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:57
S47	16	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) same ((young\$2 adj2 modulus) (tensile adj2 (stress strain)) (modulus adj2 elasticity)) not S45 and (GPa "N/cm2" "cm.sup.2")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 13:57
S51	85	347/68.ccls. and (pzt piezoelectric piezo-electric) and electrode near2 ("Pt" Platinum)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 14:27
S52	89	347/68.ccls. and (pzt piezoelectric piezo-electric) and electrode near2 ("Pt" Platinum "Ir" iridium)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 14:29
S53	25	347/68.ccls. and (pzt piezoelectric piezo-electric) and electrode near2 ("Pt" Platinum) and electrode near2 ("Ir" iridium)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 14:29
S54	103	((protective protection insulation insulating insulated) near3 (layer film)) near3 (compressive) and (electrode same (stress near3 tensile))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 15:11
S55	17	(pzt piezoelectric piezo-electric) and ((protective protection insulation insulating insulated) near3 (layer film)) near3 (compressive) and (electrode same (stress near3 tensile))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 15:28

S62	73	347/68,70.ccls. and ((upper top first second) adj2 electrode) near4 ("Pt" platinum) and @ad<"20040924"	US-PGPUB; USPAT; USOCR; DERWENT	OR	ON	2008/08/14 15:46
S63	17	(pzt piezoelectric piezo-electric) with ((protective protection insulation insulating insulated) near3 (layer film)) and ((protective protection insulation insulating insulated) near3 (layer film)) near4 (stress) and (electrode) near3 stress and stress near4 compressive	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 16:06
S68	0	(electrode near3 lead near3 aluminum) and "20020080213".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 18:42
S72	4	347/68,70.ccls. and (electrode near3 lead near3 (aluminum "AL"))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 18:44
S73	66	347/68,70.ccls. and (electrode near3 (aluminum "AL"))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 18:45
S74	66	"347".clas. and (electrode near3 lead near3 (aluminum "AL"))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 18:49
S77	1	"347".clas. and (electrode near3 (connector lead) near3 (aluminum "AL")) not S74	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/08/14 19:02

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